

EST. 1/1/1992

B⁴ 15. (amended) The method for manufacturing a carbonaceous complex structure according to claim 14 wherein

a first electrode, said carbonaceous thin film, said fullerene thin film and a second electrode are layered in this order on said substrate.

B⁵ 17. (amended) The method for manufacturing a carbonaceous complex structure according to claim 12 further comprising the step of

layering a pair of spaced apart electrodes on said carbonaceous thin film such that said fullerene thin film is formed at least in the space between said electrodes.

B⁶ 20. (amended) The method for manufacturing a carbonaceous complex structure according to claim 19 wherein the fullerene polymerization method is a plasma polymerization method, a micro-wave polymerization method, an electrolytic polymerization method, an electron beam polymerization method, an X-ray polymerization method or a photopolymerization method.

C⁶ 21. (amended) The method for manufacturing a carbonaceous complex structure according to claim 12 wherein

said fullerene thin film is formed by vapor deposition of fullerene molecules to form a vapor-deposited film and then illuminating said film of fullerene molecules by electromagnetic waves to polymerize said fullerene molecules.

22. (amended) The method for manufacturing a carbonaceous complex structure according to claim 21 wherein

the film thickness of said vapor-deposited film is measured and controlled.

23. (amended) The method for manufacturing a carbonaceous complex structure according to claim 22 wherein

said film thickness is measured by a film thickness meter arranged in a vacuum chamber.